

JUN 1 4 2002

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TC 1700

Case Docket No. ASMJP.032AUS Date: June 6, 2002

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In re application of:

Fukuda, et al.

App. No.

09/511,934

Filed

February 24, 2000

For

THIN-FILM FORMING

APPARATUS HAVING AN AUTOMATIC CLEANING FUNCTION FOR CLEANING

THE INSIDE

Examiner

R. Kackar

Art Unit

1763

I hereby certify that this correspondence and all marked attachments are being deposited with the United States Postal Service as first class mail in an envelope addressed to: United States Patent and Trademark Office, P.O. Box 2327, Arlington, VA 22202, on

June 6, 2002

Gordon H. Olson, Reg. No. 20,319

UNITED STATES PATENT AND TRADEMARK OFFICE P.O. Box 2327 Arlington, VA 22202

Sir:

Transmitted herewith is an amendment in the above-identified application.

The fee has been calculated as shown below:

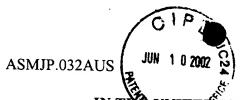
CLAIMS AS FILED						
	CLAIMS REMAINING AFTER AMENDMENT		HIGHEST NO. PREVIOUSLY PAID FOR	PRESENT EXTRA	RATE	ADDITIONAL FEE
Total Claims	20	_	20	= 0 ×	\$18	= \$0
Independent Claims	2		3	= 0 ×	\$84	= \$0
TOTAL ADDITIONAL FEE FOR THIS AMENDMENT					\$0	

- (X) Amendment in six (6) pages.
- (X) Return prepaid postcard.
- (X) Please charge any additional fees, including any fees for additional extension of time, or credit overpayment to Deposit Account No. 11-1410.

Gordon H. Olson Registration No. 20,319

Attorney of Record

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## QUNITED STATES PATENT AND TRADEMARK OFFICE

Applicant Fukuda et al. Appl. No. 09/511,934

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For THIN-FILM **FORMING** APPARATUS HAVING AN

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COPY OF PAPERS

## **AMENDMENT**

**Assistant Commissioner for Patents** Washington, D.C. 20231

Dear Sir:

In response to the Office Action mailed March 7, 2002, please amend the abovecaptioned application as follows:

## IN THE CLAIMS:

Please amend Claims 1-4 as follows:

1. (Amended) A thin-film forming apparatus comprising:

a reaction chamber for forming at a film formation temperature a thin film on a workpiece placed on a susceptor provided in the reaction chamber, said susceptor being provided with a heater for heating the workpiece, said reaction chamber being provided with a conveyer for loading and unloading the workpiece into and from the reaction chamber; and

a cleaning device for cleaning unwanted deposits adhering to the inside of the reaction chamber at predetermined intervals, said cleaning device comprising:

(i) a cleaning gas controller for introducing a cleaning gas into the reaction chamber and evacuating the reaction chamber after the cleaning treatment;

